



PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of

Minoru KATAYAMA et al.

Group Art Unit: 2856

Application No.: 09/690,590

Examiner: M. Cygan

Filed: October 18, 2000

Docket No.: 107612

For: SURFACE TEXTURE MEASURING MACHINE, LEVELING DEVICE FOR
SURFACE TEXTURE MEASURING MACHINE AND ORIENTATION-ADJUSTING
METHOD OF WORKPIECE OF SURFACE TEXTURE MEASURING MACHINE

AMENDMENT UNDER 37 C.F.R. §1.111

Director of the U.S. Patent and Trademark Office
Washington, D.C. 20231

Sir:

In reply to the Office Action mailed December 13, 2001, please amend the above-identified application as follows:

IN THE SPECIFICATION:

Page 10, lines 18-29, delete current paragraph and insert therefore:

a' A workpiece orientation adjustment stage 10 is provided on the base 11, the workpiece orientation adjustment stage 10 having a Y-axis stage 12 capable of moving in Y-axis direction (a direction orthogonal with X-axis direction [measurement direction] on a horizontal plane), a R-axis stage 13 provided on the Y-axis stage 12 and being capable of seesawing in R-axis direction (a direction orthogonal with the X-axis direction on a perpendicular plane), and a rotary stage 14 provided on the R-axis stage 13 and being rotatable in θ direction. Further, a column 15 stands on a right side of the rear of the base 11 as illustrated, the column 15 having a Z-axis slider 16 vertically movable along Z-axis